Search Notes

Application/Control No.	Applicant(s)/Patent under Reexamination
10/516,824	OTAGURO, TETSUNORI
Examiner	Art Unit
Phil J. Kauffman	3652

SEARCHED					
Class	Subclass	Date	Examiner		
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INTERFERENCE SEARCHED					
Class	Subclass	Ďate	Examiner		
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SEARCH NOTES (INCLUDING SEARCH STRATEGY)				
	DATE	EXMR		
414/217 US only	7/28/2006	PJK		
wafer and manufacture and FOUP S17 JPO DERWENT	7/28/2006	PJK		
wafer and manufacture and SMIF S18 JPO DERWENT	7/28/2006	PJK		
wafer and manufacture and container S19 JPO DERWENT	7/28/2006	PJK		
(container or smif or FOUP) and manufacture and system and ceiling JPO DERWENT	7/28/2006	PJK		
(container or smif or FOUP) and manufacture and system and (overhead or "over head") JPO DERWENT	7/28/2006	pjk		
East search attached		РЈК		
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